

Amendments to the Claims:

1. (Currently Amended) A bimorph mirror presenting first and second layers of piezoelectric ceramic together with at least one electrode serving to vary at least one curvature of the mirror as a function of at least one electrical voltage applied to the piezoelectric ceramics, the mirror being characterized in that the first and second layers (1,2) of piezoelectric ceramic are separated by a central core (5) of material ~~such as glass or silica~~, which forms a semirigid beam, the thickness (e) of the central core (5) lying in the range 1 mm to 80 mm.
2. (Currently Amended) A bimorph mirror according to claim 1, ~~characterized in that~~ wherein the thickness (e) of the central core (5) lies in the range 2 mm to 80 mm.
3. (Currently Amended) A bimorph mirror according to claim 2, ~~characterized in that~~ wherein the thickness (e) of the central core (5) lies in the range 5 mm to 80 mm.
4. (Currently Amended) A bimorph mirror according to ~~any preceding~~ claim 1, ~~characterized in that~~ wherein said central core is constituted by a material selected from glass and silica.
5. (Currently Amended) A bimorph mirror according to ~~any preceding~~ claim 1, ~~characterized in that~~ wherein the first and second layers (1,2) of piezoelectric ceramic are sandwiched between two skin layers (3,4), e.g. of glass or of silicon.
6. (Currently Amended) A bimorph mirror according to ~~any preceding~~ claim 1, ~~characterized in that~~ wherein it presents a total thickness (E) lying in the range 10 mm to 150 mm.
7. (Currently Amended) A bimorph mirror according to ~~any preceding~~ claim 1, ~~characterized in that~~ wherein the first and second layers (1,2) of piezoelectric ceramic are formed by a plurality of ceramic elements placed side by side in at least one direction along

section planes, and ~~in that~~ the section planes ~~(212, 223, ...)~~ of said second layer ~~(2)~~ are offset in at least one direction relative to the section planes ~~(112, 123, ...)~~ of said first layer ~~(1)~~.

8. (Currently Amended) A bimorph mirror according to claim 7, ~~characterized in that~~ wherein said offset between the piezoelectric elements in at least one direction is equal to half a pitch P at which the piezoelectric elements are disposed in said direction.

9. (Currently Amended) A bimorph mirror presenting first and second layers of piezoelement ceramic, together with at least one electrode enabling at least one curvature of the mirror to be caused to vary as a function of at least one electrical voltage applied to the piezoelectric ceramics, the mirror being characterized in that the first and second layers ~~(1, 2)~~ of piezoelectric ceramic are made up of respective pluralities of ceramic elements placed side by side in at least one direction along section planes, and in that the section planes ~~(212, 223, ...)~~ of said second layer ~~(2)~~ are offset in at least one direction relative to the section plane ~~(112, 123, ...)~~ of said first layer ~~(1)~~.

10. (Currently Amended) A bimorph mirror according to claim 9, ~~characterized in that~~ wherein said offset between the piezoelectric elements in at least one direction is equal to half a pitch P at which the piezoelectric elements are placed in said direction.